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(12) **United States Design Patent**
Matoba et al.

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(54) **COVER FOR AN ELECTRON MICROSCOPE**

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(**) Term: **14 Years**

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(30) **Foreign Application Priority Data**

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(51) **LOC (10) Cl.** **16-01**
(52) **U.S. Cl.**
CPC ***H01J 37/26*** (2013.01)
USPC **D16/131**
(58) **Field of Classification Search**
CPC A47B 81/00
USPC D16/131, 130; D24/216, 232; D15/85, D15/86; 250/310, 311, 440.11; D10/81; 422/63, 64
See application file for complete search history.

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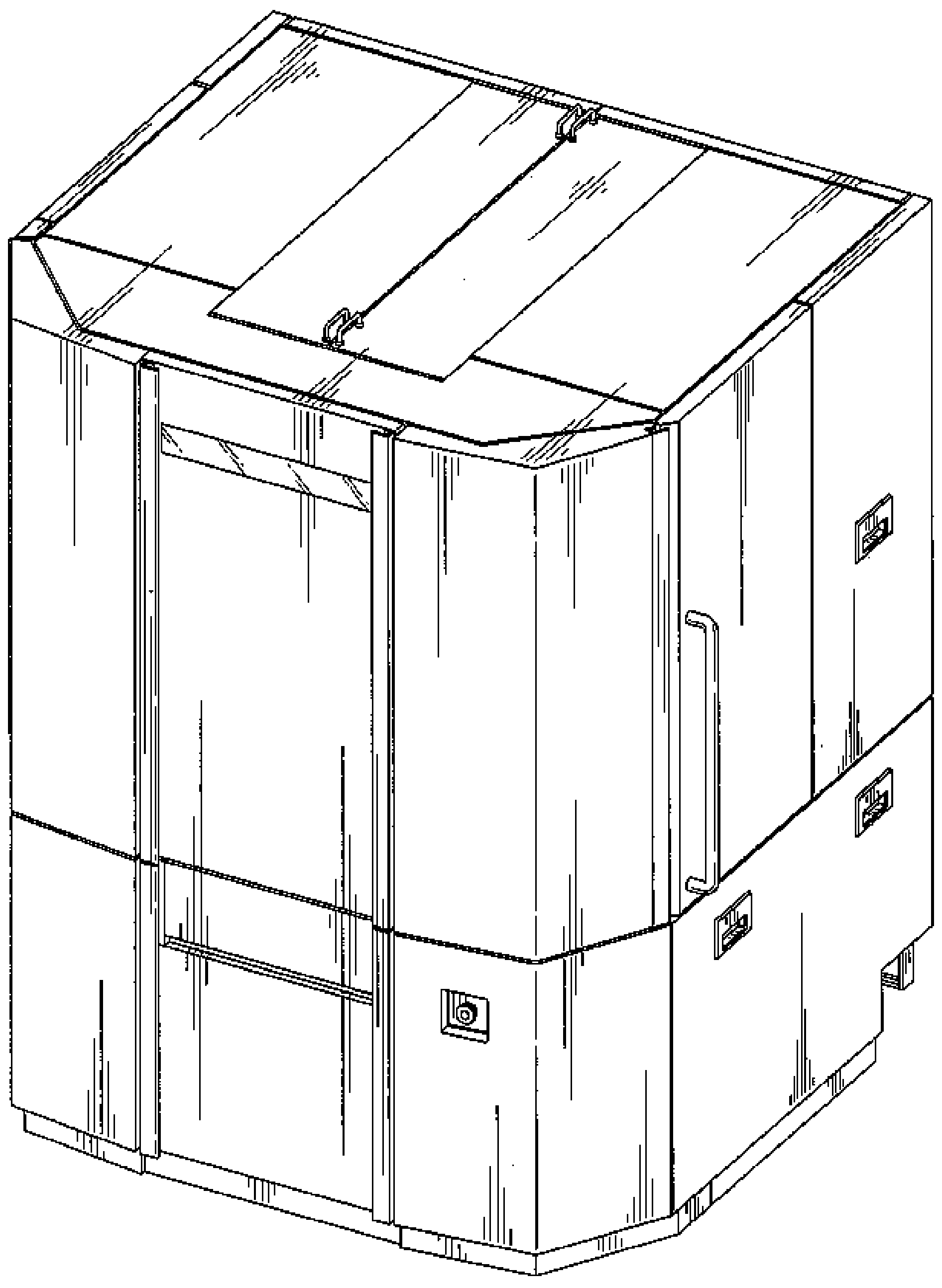
(57) **CLAIM**

We claim the ornamental design for a cover for an electron microscope, as shown and described.

DESCRIPTION

FIG. **1** is a front, top and right side perspective view of a cover for an electron microscope showing our new design;
FIG. **2** is a front elevational view thereof;
FIG. **3** is a rear elevational view thereof;
FIG. **4** is a left side elevational view thereof;
FIG. **5** is a right side elevational view thereof;
FIG. **6** is a top plan view thereof;
FIG. **7** is a bottom plan view thereof;
FIG. **8** is a perspective view thereof shown in an opened position; and,
FIG. **9** is a perspective view thereof shown in another opened position.

1 Claim, 9 Drawing Sheets



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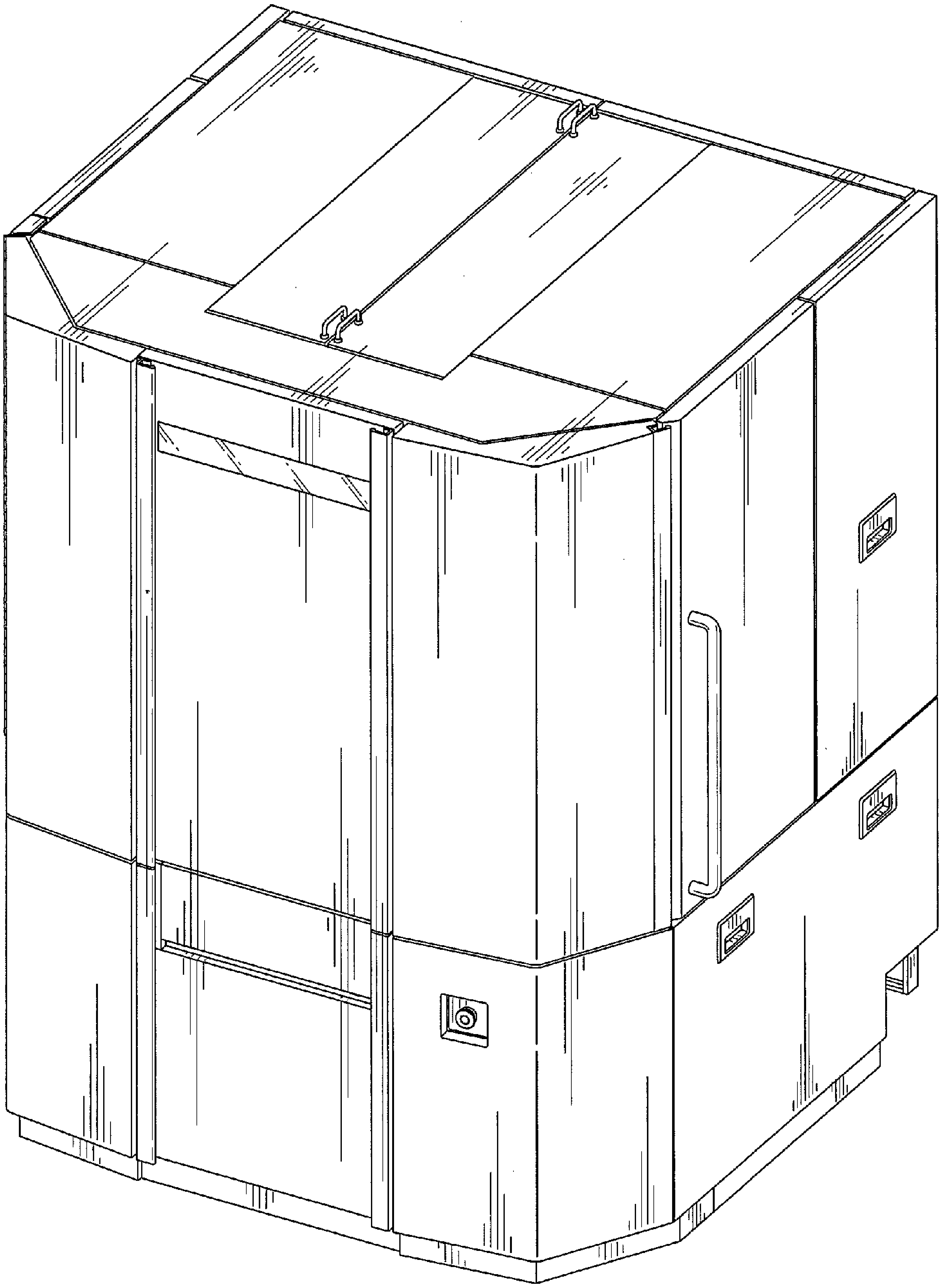

FIG. 1

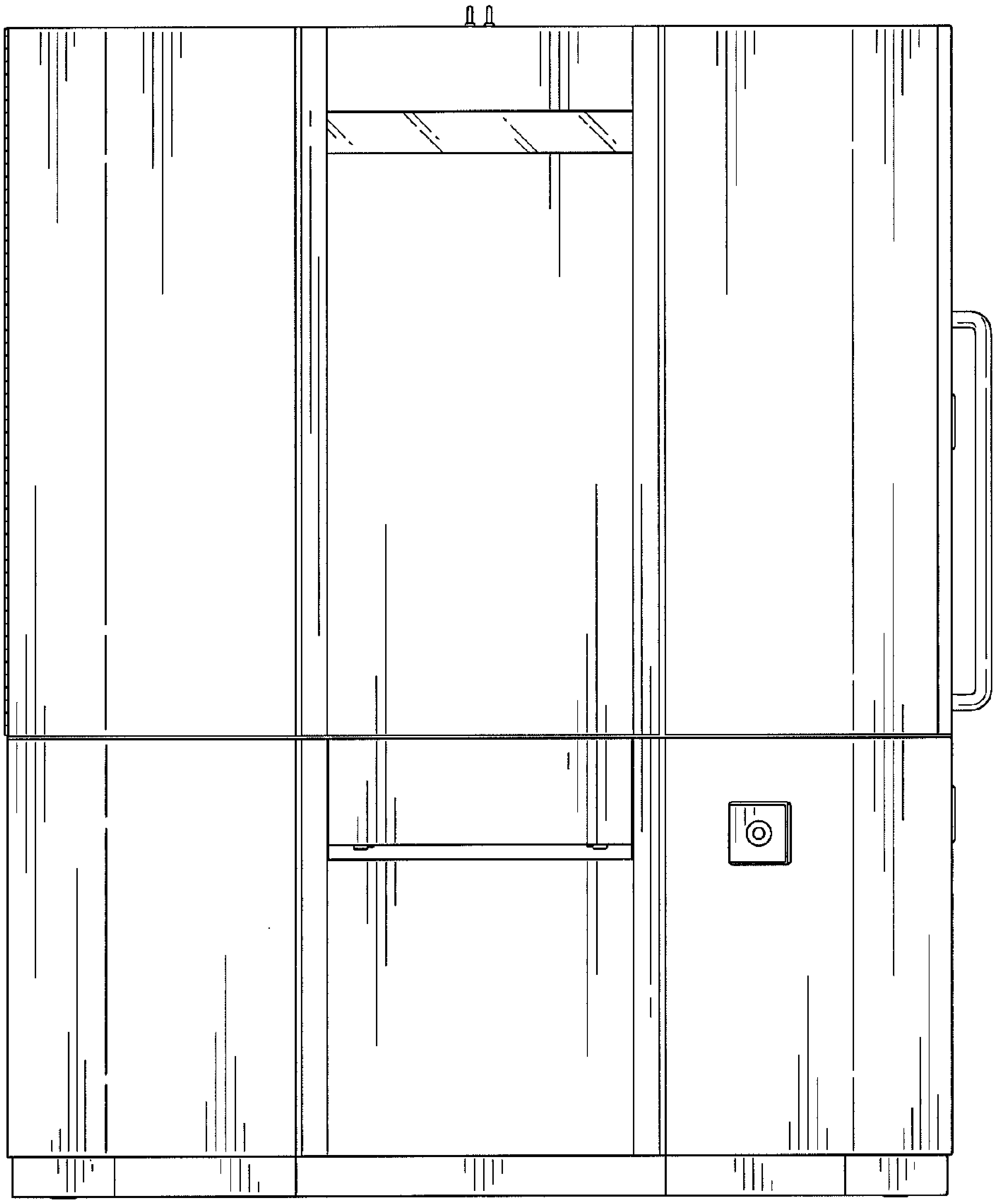

FIG. 2

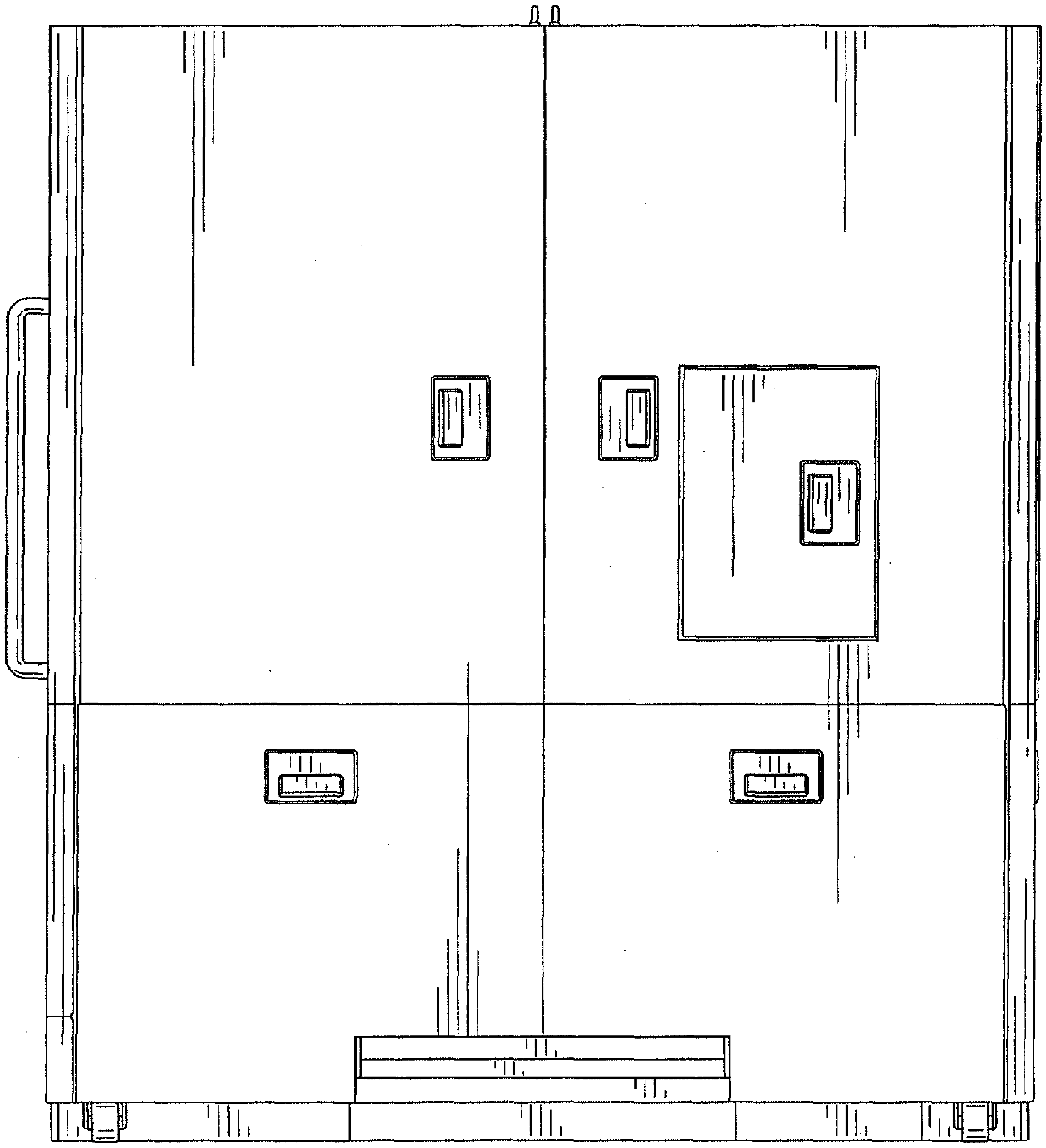

FIG. 3

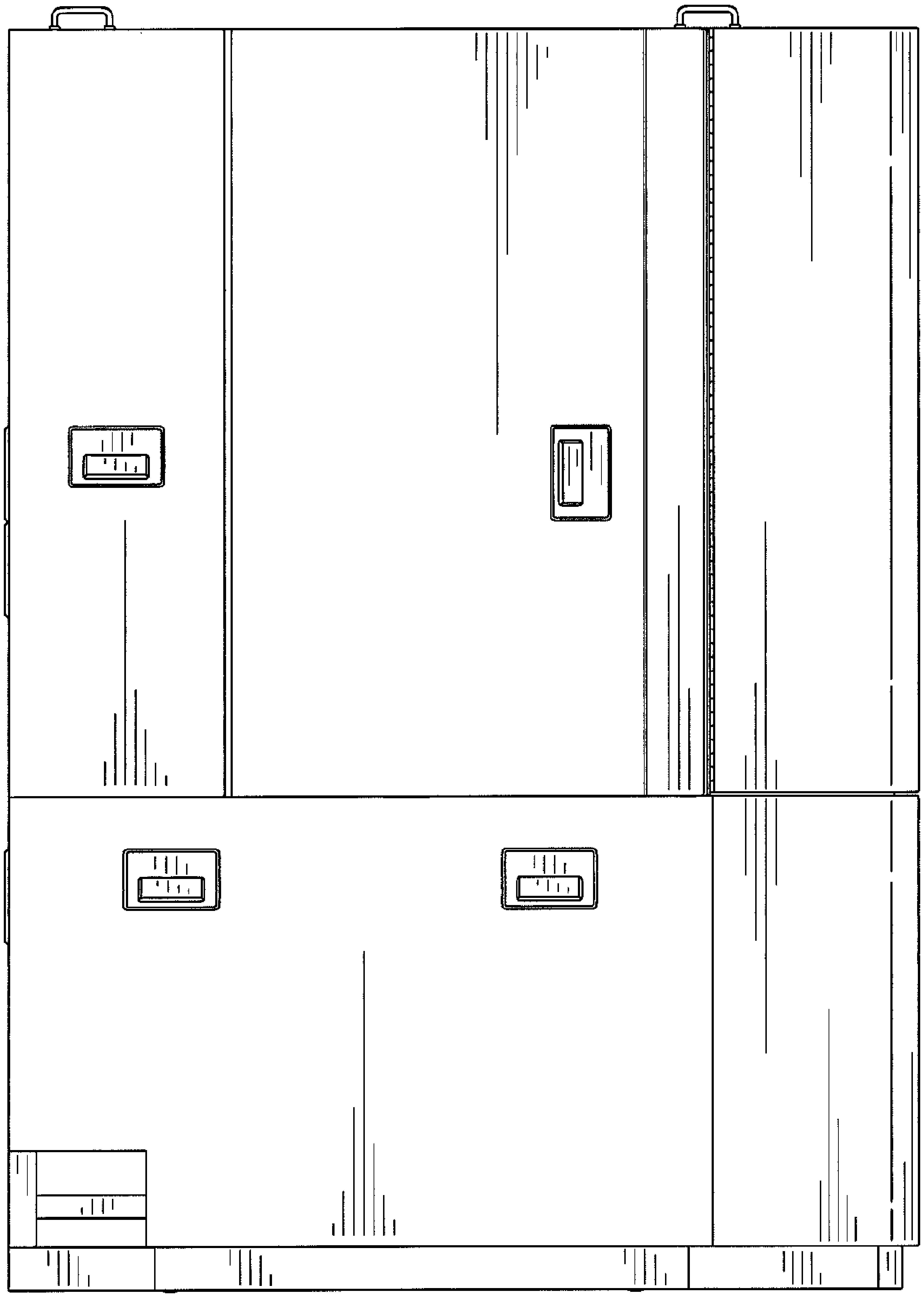

FIG. 4

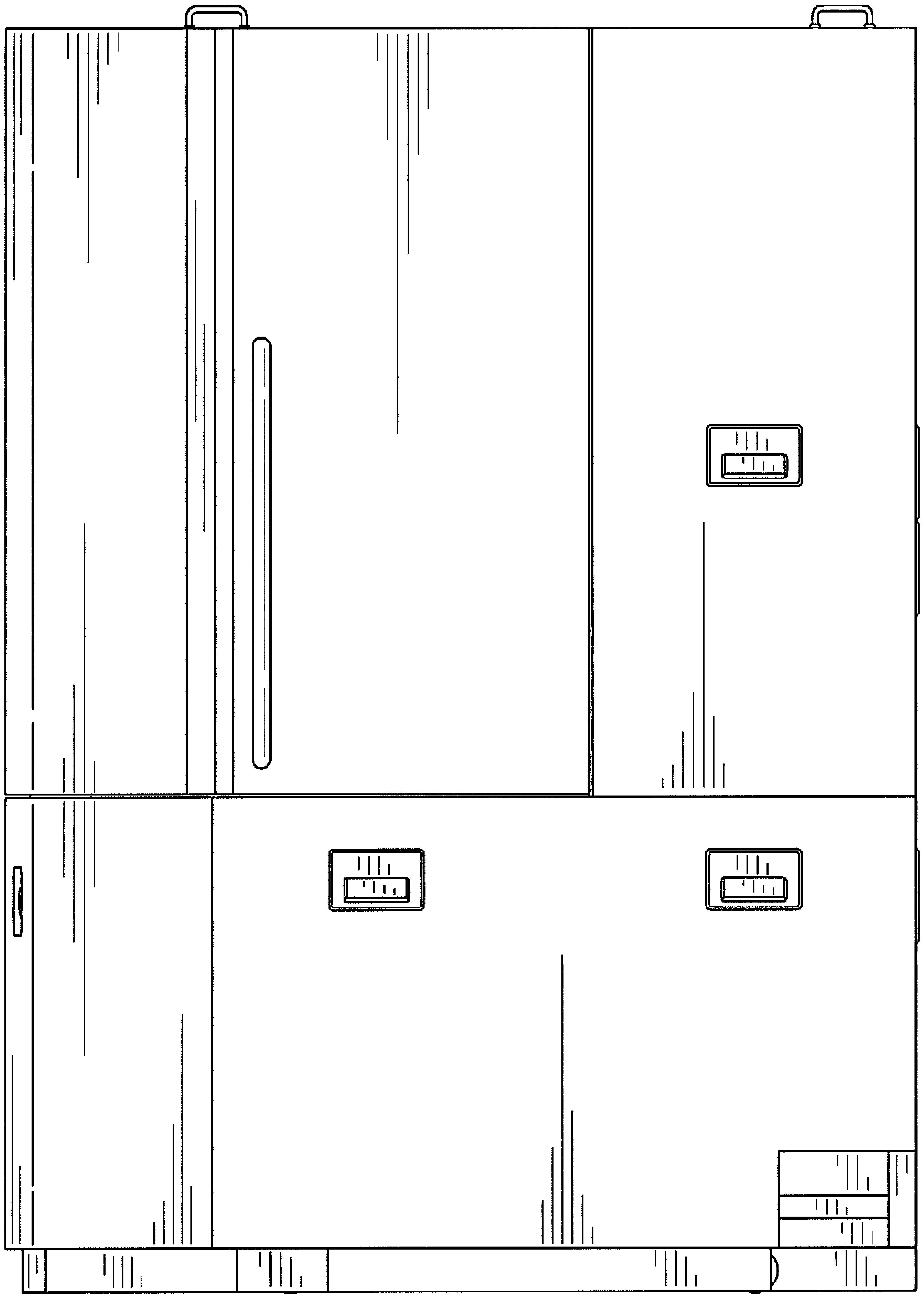

FIG. 5

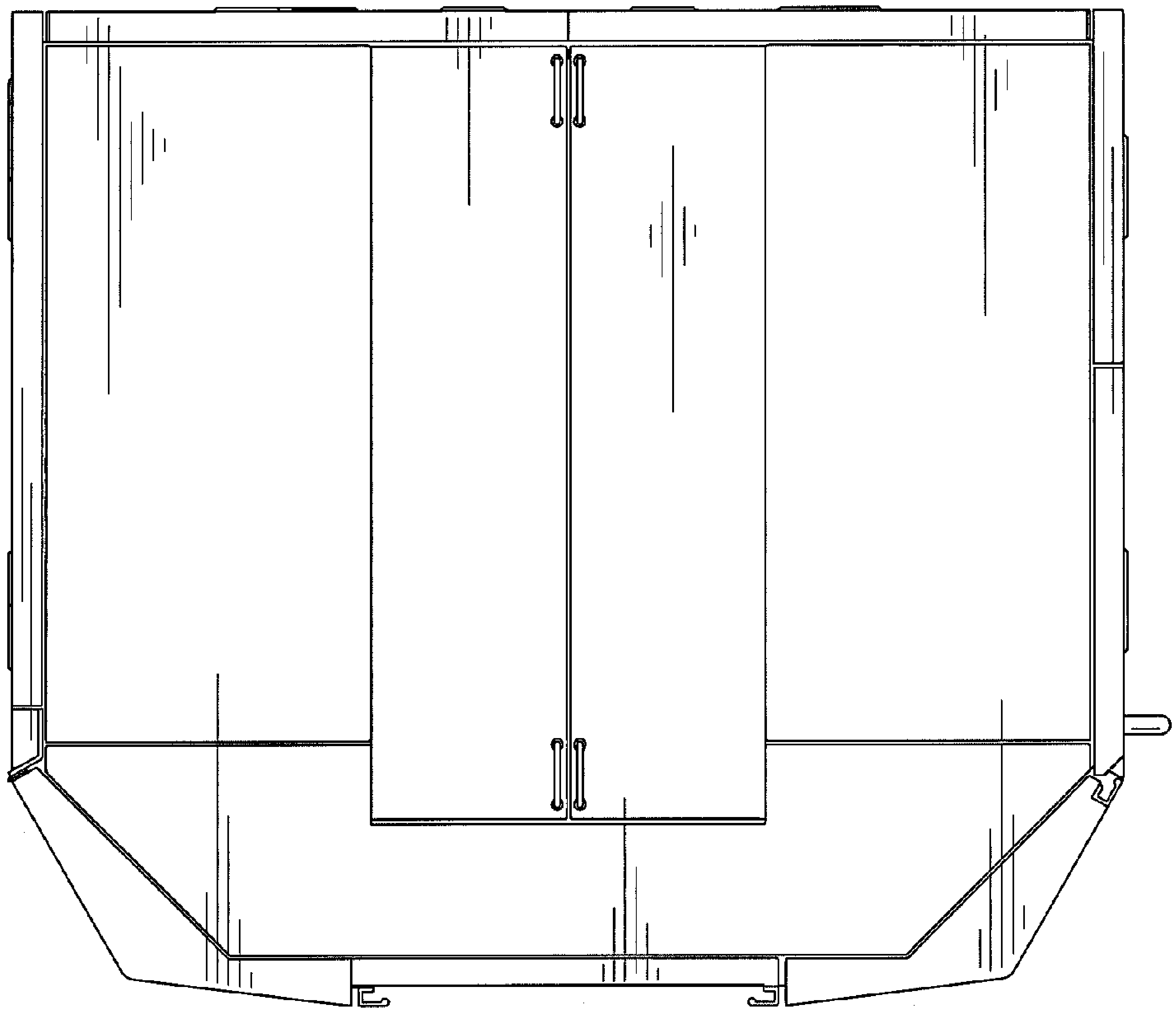

FIG. 6

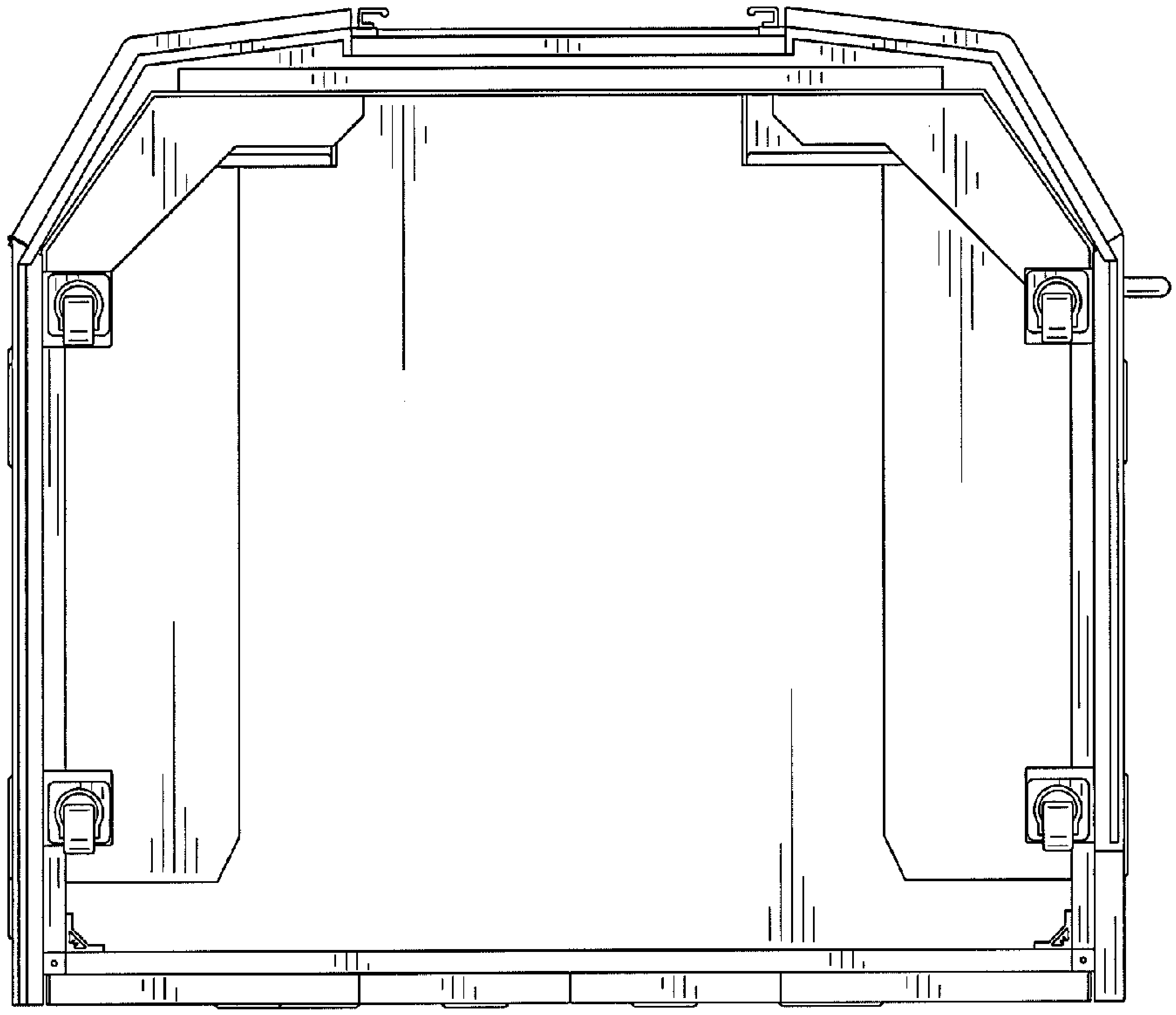

FIG. 7

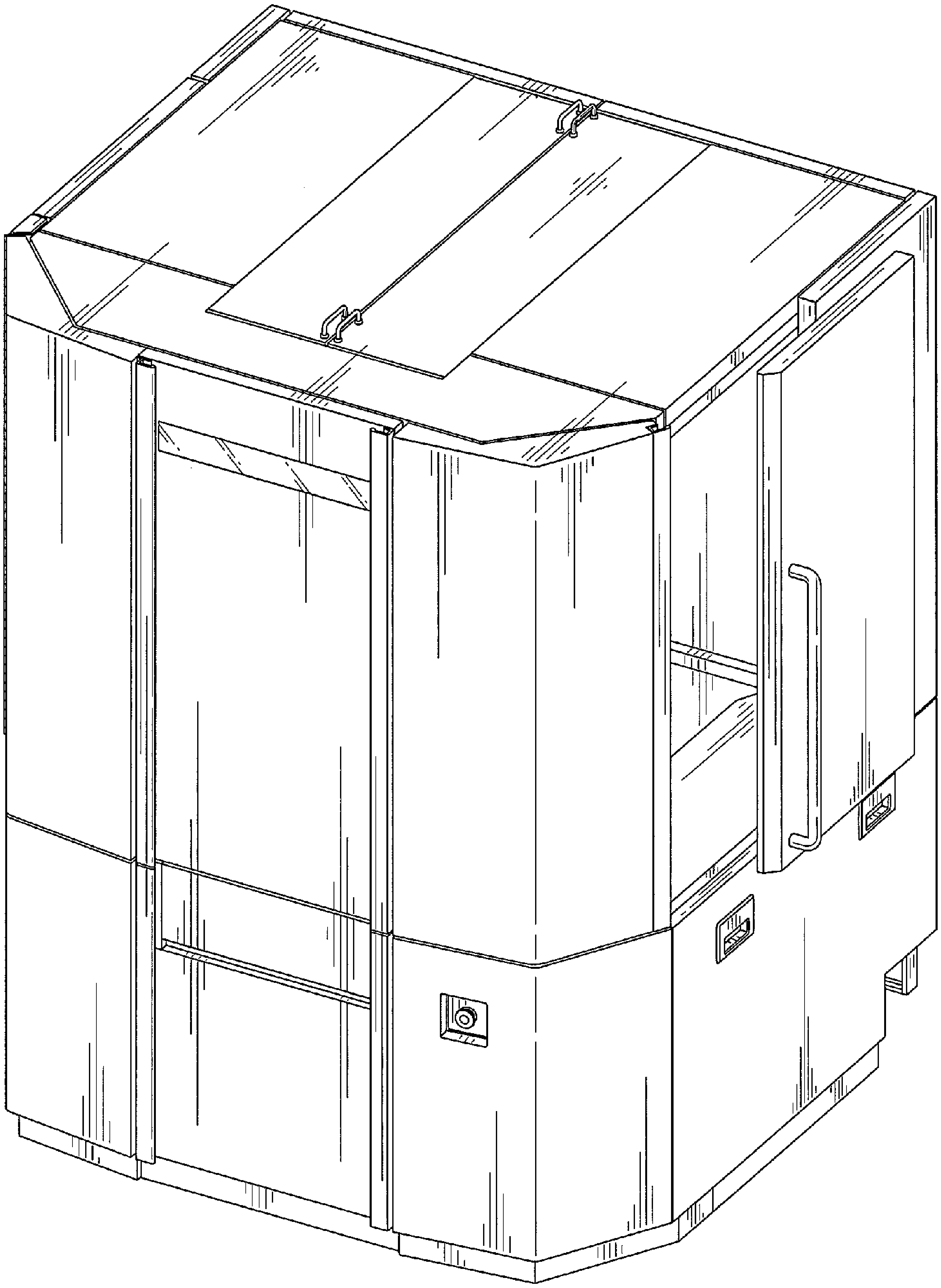

FIG. 8

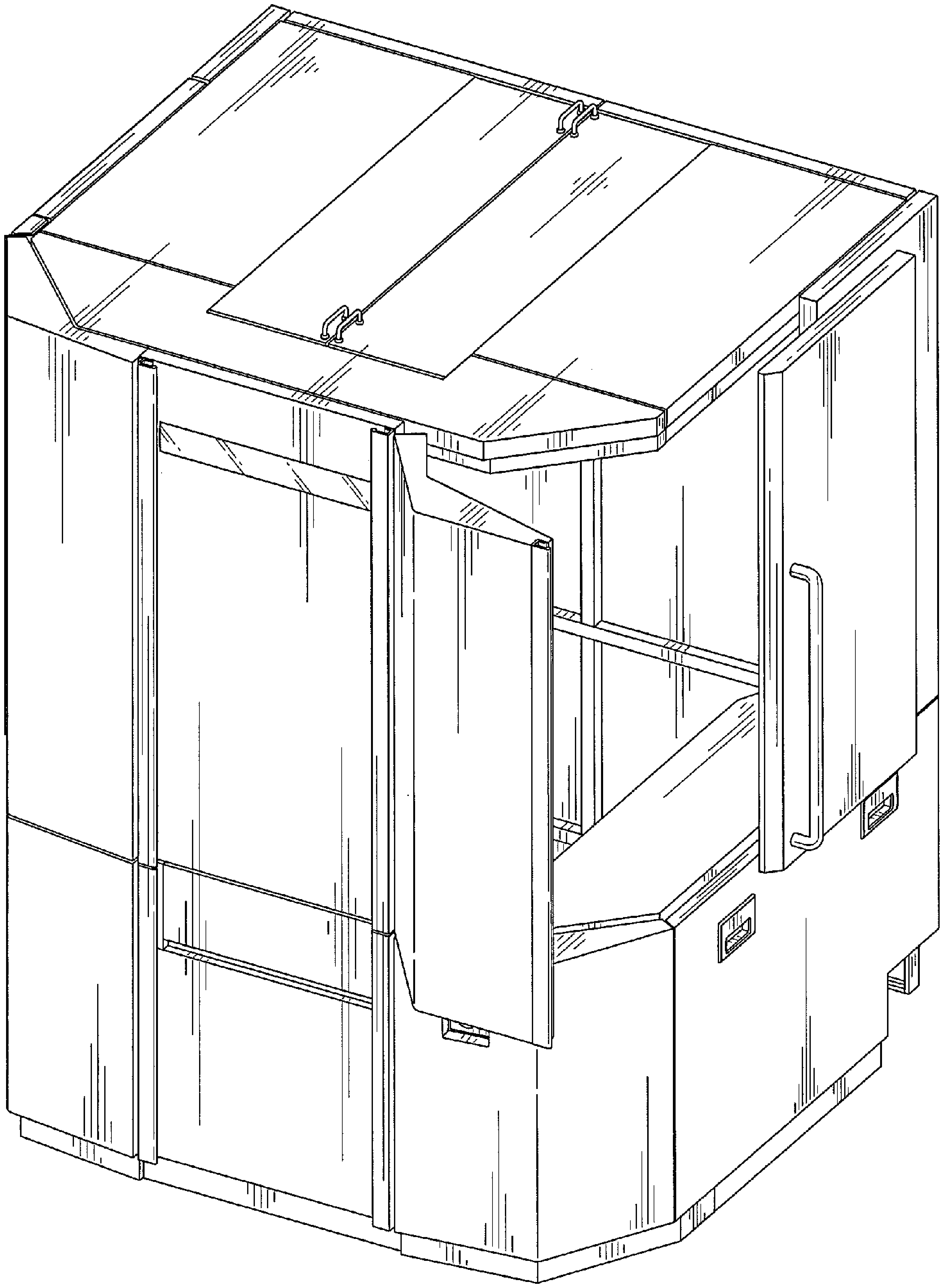

FIG. 9